



EXPRESS MAIL NO. EV207709109US

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Antonius Henricus Elisabeth Breuls et al.  
Application No. : 09/839,028  
Filed : April 19, 2001  
For : PCVD APPARATUS AND A METHOD OF MANUFACTURING  
AN OPTICAL FIBER, A PREFORM ROD AND A JACKET TUBE  
AS WELL AS THE OPTICAL FIBER MANUFACTURED  
THEREWITH

Examiner : Parviz Hassanzadeh  
Art Unit : 1763  
Docket No. : 750034.427C2  
Date : March 20, 2003

Box Non-Fee Amendment  
Commissioner for Patents  
Washington, DC 20231

AMENDMENT

Commissioner for Patents:

In response to the Office Action dated December 23, 2002, please amend the application as follows:

In the Claims:

Please add new claim 7 to read as follows:

7. (New) An apparatus for performing Plasma Chemical Vapor Deposition, whereby one or more layers of silica can be deposited on an elongated vitreous substrate, the apparatus comprising an elongated microwave guide which emerges into a resonant cavity which is substantially cylindrically symmetric about a cylindrical axis, along which axis the substrate can be positioned, the cavity being substantially annular in form, with an inner cylindrical wall and an outer cylindrical wall, the inner cylindrical wall comprising a slit which extends in a full